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	APPLICANT Hiroi, Takashi et al.	
	FILING DATE Herewith	GROUP 2877 (Expected)

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U. S. PATENT DOCUMENTS

EXAMINER INITIAL	PATENT NUMBER	PATENT DATE	NAME	CLASS/ SUBCLASS	FILING DATE
JPB	5,085,517	02/92	CHADWICK et al.	356	394
JPB	5,502,306	03/96	MEISBURGER et al.	250	310
JPB	4,805,089	02/89	LANE et al.	364	188
JPB	4,843,538	06/89	LANE et al.	364	188
JPB	5,018,082	05/91	OBATA et al.	364	521
JPB	5,862,055	01/99	CHEN et al.	364	468.28
JPB	5,841,893	11/98	ISHIKAWA et al.	382	145
JPB	5,578,821	11/96	MEISBERGER et al.	350	310

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION	
					YES	NO
JPB	JP-3-167456	07/91	JAPAN			X
JPB	JP-5-258703	10/93	JAPAN			X
JPB	JP-63-32604	02/88	JAPAN			X
JPB	JP-61-290641	12/86	JAPAN		Abstract	
JPB	JP-64-84555	03/89	JAPAN		Abstract	
JPB	JP-64-84555	03/89	JAPAN		Abstract	
JPB	JP-2-148272	06/90	JAPAN		Abstract	
JPB	JP-4-253352	09/92	JAPAN		Abstract	
JPB	JP-10-189668	07/98	JAPAN		Abstract	
JPB	JP-7-282764	10/95	JAPAN		Abstract	
JPB	JP-10-302702	11/98	JAPAN		Abstract	
JPB	JP-10-302704	11-98	JAPAN		Abstract	

OTHER DOCUMENTS

EXAMINER INITIAL	AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
JPB	"Monthly Semiconductor World" August 1995, pp. 96-99.
JPB	"Journal of Vacuum Science Technology B", Vol.9, No.6, 1991, pp. 3005-3009.
JPB	"Journal of Vacuum Science Technology B", Vol.10, No.6, 1992, pp. 2804-2808.

EXAMINER <i>Jack Berman</i>	DATE CONSIDERED 8/21/01
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